



AF/1765
JEW
PATENT
81839.0107

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Makoto IIDA, et al.

Serial No: 10/009,910

Filed: December 12, 2001

For: SILICON WAFER, SILICON EPITAXIAL
WAFER, ANNEAL WAFER AND METHOD
FOR PRODUCING THEM

Art Unit: 1765

Examiner: Matthew J. Song

I hereby certify that this correspondence
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November 2, 2004

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Name

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Date

**NOTICE OF APPEAL FROM THE PRIMARY
EXAMINER TO THE BOARD OF APPEALS**

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Applicant hereby appeals to the Board of Appeals from the decision dated June 24, 2004 of the Primary Examiner finally rejecting claims 1-10. The item(s) checked below are appropriate:

1. ☒ A two- month extension of time to respond to the final rejection is hereby requested under 37 C.F.R. § 1.136 and is enclosed with the proper fee.
2. ☒ A timely response to the final rejection has been filed, as provided in 841 O.G. 1411.
3. The application is on behalf of:
 - ☐ a small entity
Applicants claims small entity status.
 - ☒ other than a small entity.

11/08/2004 RMEBRAHT 00000002 10009910

01 FC:1401

340.00 DP

☒ Fee ☐ \$165 ☒ \$340

☒ enclosed.

☐ not required (fee paid in prior appeal).

☒ charged to Deposit Account No. 50-1314 if any additional fees are required.

(An additional copy of this Notice is enclosed.)

Respectfully submitted,

HOGAN & HARTSON L.L.P.

Date: November 2, 2004

By: 

John P. Scherlacher

Registration No. 23,009

Attorney for Applicant(s)

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